

# United States Patent and Trademark Office

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER OF PATENTS AND TRADEMARKS Washington, D.C. 20231 www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/207,972	12/09/1998	MARK I. GARDNER	5500-36100	7507
- 75	90 11/19/2002			
KEVIN L DA	FFER		EXAMINER  WARREN, MATTHEW E  ART UNIT PAPER NUMBER	NER
CONLEY ROS P O BOX 398			WARREN, M	ATTHEW E
AUSTIN, TX	78767-0398		ART UNIT	PAPER NUMBER
			2815	11-
			DATE MAIL ED: 11/19/2002 / (0)	

Please find below and/or attached an Office communication concerning this application or proceeding.

_			In
` ' '	Application No.	Applicant(s)	
	09/207,972	GARDNER ET AL.	
Office Action Summary	Examiner	Art Unit	
	Matthew E. Warren	2815	
The MAILING DATE of this communica Period for Reply	tion appears on the cover sheet wit	the correspondence address	
A SHORTENED STATUTORY PERIOD FOR THE MAILING DATE OF THIS COMMUNICA  - Extensions of time may be available under the provisions of 3 after SIX (6) MONTHS from the mailing date of this communic  - If the period for reply specified above, the maximum statutor  - Failure to reply within the set or extended period for reply will,  - Any reply received by the Office later than three months after earned patent term adjustment. See 37 CFR 1.704(b).	TION. 7 CFR 1.136(a). In no event, however, may a reseation. ays, a reply within the statutory minimum of thirty by period will apply and will expire SIX (6) MONT by statute, cause the application to become ABA	oly be timely filed  (30) days will be considered timely.  HS from the mailing date of this communication  NDONED (35 U.S.C. § 133).	ı.
Status			
1) Responsive to communication(s) filed			
	This action is non-final.	ore prograution as to the morits i	in
3) Since this application is in condition for closed in accordance with the practice Disposition of Claims			5
4)⊠ Claim(s) <u>16-33</u> is/are pending in the ap	oplication.		
4a) Of the above claim(s) is/are			
5) Claim(s) <u>24-29,32 and 33</u> is/are allowe			
6)⊠ Claim(s) <u>16-21,23,30 and 31</u> is/are reje			
7) Claim(s) 22 is/are objected to.			
8) Claim(s) are subject to restrictio	n and/or election requirement.		
Application Papers			
9) ☐ The specification is objected to by the E	xaminer.		
10) The drawing(s) filed on is/are: a)	$\square$ accepted or b) $\square$ objected to by th	e Examiner.	
Applicant may not request that any object			
11)☐ The proposed drawing correction filed o		sapproved by the Examiner.	
If approved, corrected drawings are requi			
12) ☐ The oath or declaration is objected to by	the Examiner.		
Priority under 35 U.S.C. §§ 119 and 120			
13) Acknowledgment is made of a claim fo	r foreign priority under 35 U.S.C. §	119(a)-(d) or (f).	
a) ☐ All b) ☐ Some * c) ☐ None of:			
<ol> <li>Certified copies of the priority do</li> </ol>			
	cuments have been received in Ap		
<ul> <li>3. Copies of the certified copies of application from the Internati</li> <li>* See the attached detailed Office action f</li> </ul>	the priority documents have been ional Bureau (PCT Rule 17.2(a)). for a list of the certified copies not i		
14) Acknowledgment is made of a claim for	domestic priority under 35 U.S.C.	3 119(e) (to a provisional applicati	on).
a) ☐ The translation of the foreign langu 15)☐ Acknowledgment is made of a claim for	uage provisional application has be	en received.	
Attachment(s)		<del></del>	
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-3) Information Disclosure Statement(s) (PTO-1449) Page	9-948) 5) Notice of I	ummary (PTO-413) Paper No(s)  Iformal Patent Application (PTO-152)	

Art Unit: 2815

#### **DETAILED ACTION**

This Office Action is in response to the Remarks filed on August 23, 2002.

# Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 16-19, 21, 23, 30, and 31 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kizilyalli et al. (US 6,320,238 B1) in view of Wu (US 5,880,508).

Kizilyalli et al (fig. 1) a semiconductor device comprising a semiconductor substrate (1) and low trap density oxide layer (102) formed on the substrate (col. 6, lines 49-55). A high dielectric constant film (103), such as the metal oxide tantalum pentoxide, is formed on the oxide layer. Ta<sub>2</sub>O<sub>5</sub> has a dielectric constant of which is greater than 5 or 20 as cited in the applicant's claimed invention. A gate conductor (104) is arranged on the high dielectric constant film. The silicon oxide film is less than 10 angstroms thick (col. 4, lines 31-34). Kizilyalli et al. shows all of the elements of the claims except the low trap density layer (oxide layer) having nitrogen which Wu discloses (col. 1, lines 38-43) to reduce leakage currents in the layer. Therefore it would have been obvious to one of ordinary skill in the art at the time the invention was made to modify the low trap density layer of Kizilyalli et al by adding nitrogen as taught by Wu to suppress leakage current in the layer.

Application/Control Number: 09/207,972

Art Unit: 2815

Claim 20 is rejected under 35 U.S.C. 103(a) as being unpatentable over Kizilyalli et al. (US 6,320,238 B1) in view of Wu (US 5,880,508) as applied to claim 16 above, and further in view of Chou (US 5,994,734).

over Kizilyalli in view of Wu shows all of the elements of the claims except the additional gate dielectric and gate conductor formed between the nitrogen-containing oxide and the substrate. Chou shows (figs. 3f, 3g) a semiconductor device having an additional gate conductor layer (23) and a gate dielectric (22) formed between a dielectric stack and the substrate (20) to form a non volatile memory device. Therefore it would have been obvious to one of ordinary skill in the art at the time the invention was made to modify the semiconductor device of over Kizilyalli in view of Wu by adding an additional gate conductor and dielectric as taught by Chou to form a non volatile memory device.

## Allowable Subject Matter

Claim 22 is objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

Claims 24-29, 32, and 33 are allowed.

The following is an examiner's statement of reasons for allowance: the prior art references, alone or in combination, do not show a semiconductor device having the combination of a low trap density nitrogen containing oxide on a semiconductor substrate, the nitrogen containing oxide having a thickness less that 10 Angstroms and

high-K dielectric on the nitrogen containing oxide, wherein the high-K dielectric has thickness less than 10 Angstroms also.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

## Response to Arguments

Applicant's arguments filed with respect to claims 16-23, 30, and 31 have been fully considered but they are not persuasive. The applicant primarily asserts that cited references do not show all of the elements of the claims, specifically that Kizilyalli et al. and Wu do not show a low-trap-density nitrogen-containing oxide arranged upon an upper surface of a semiconductor substrate. The applicant also asserts that the references do not provide motivation for combining. The examiner believes that the cited references show all of the elements of the claims and provide proper motivation for combining.

With respect to the arguments that the reference do not, show all of the elements of the claims, Kizilyalli specifically discloses in column 6 lines 49-55 that the device incorporates a low trap density oxide layer. Kizilyalli is only deficient in that the low trap density layer does not contain nitrogen. Wu cures the deficiency of Kizilyalli because it is taught that a gate oxide having nitride has lower leakage current than regular oxide. Within the teachings of Wu is found the motivation also. One of ordinary skill in the art

Art Unit: 2815

would know that by adding nitrogen to a gate oxide layer, leakage current is reduced. Although the combined references may not use the same methods for forming the gate dielectric as disclosed in the arguments, the structural limitations of the claims are what is relied upon and thus such arguments are not relevant. Therefore, the cited references show all of the elements of the claims, they provide proper motivation, and this action is made final.

#### Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Matthew E. Warren whose telephone number is (703) 305-0760. The examiner can normally be reached on Mon-Thurs, and alternating Fri, 9:00-5:00.

Application/Control Number: 09/207,972

Art Unit: 2815

Page 6

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eddie Lee can be reached on (703) 308-1690. The fax phone numbers for the organization where this application or proceeding is assigned are (703) 305-3432 for regular communications and (703) 308-7722 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0956.

MEW

November 18, 2002

eddie lee

SUPERMISORY PATENT EXAMINER TECHNOLOGY CENTER 2000